



Study of point- and cluster-defects in radiation-damaged silicon

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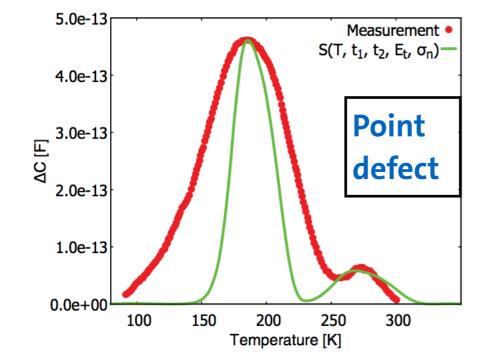


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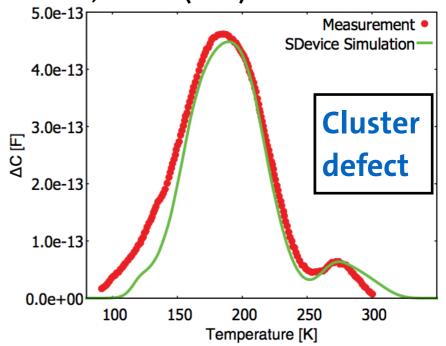


- Irradiations of silicon can produce point-like and cluster defects
- The **peak shape** of cluster-related defects recorded by **TSC** or **DLTS** differs significantly from those of point-like defects (measured peaks are broader compared to point-defects)
- Problem was studied by A. Scheinemann and A. Schenk e.g. on dislocation loops (DLs) due to ion implantation in CMOS devices



DLTS spectrum of DL compared with analytical theory for point defects:

[A. Scheinemann, A. Schenk, Phys. Stat. Solidi A211, No.1, 136-142 (2014)+ PhD Scheinemann]



DLTS simulation of DL taking into account the Coulomb repulsion energy

In this talk

- Application to silicon irradiated with electrons with 3.5 27 MeV kinetic energy
 - Formation of cluster defects is expected above 7 MeV



MODEL



Assumptions:

- Cluster \rightarrow **accumulation** of point defects
- \rightarrow change of **local potential** depending on fraction of filled states
- \rightarrow activation energy E_a of defects **depends on occupation**
- \rightarrow time (and T) dependence

Dislocation loop (DL): Potential energy vs. occupation

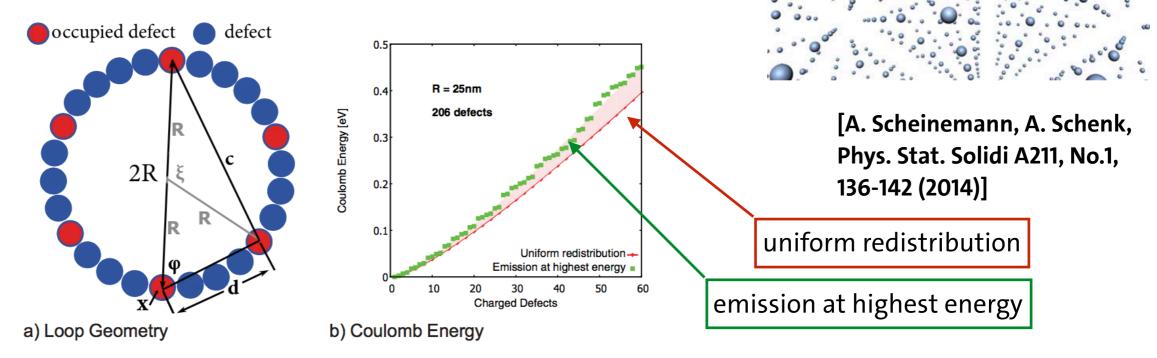


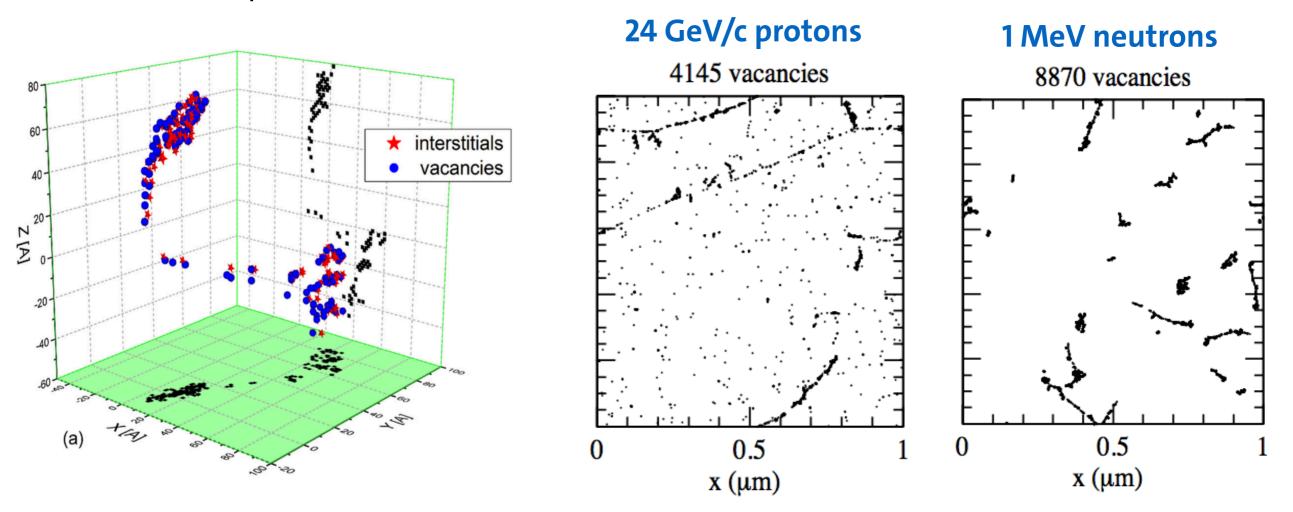
Figure 2 (a) Schematic view of DL periphery partially occupied by captured carriers with geometry used to derive the Coulomb contribution to the defect level. (b) Deviations between the assumption that captured carriers can redistribute instantaneously along the dislocation loop (solid line) and the case where they are bound to their site while capture and emission probabilities vary along the periphery of the defect with the local Coulomb energy contribution (square symbols). The shaded area indicates 15% difference from the original analytical expression.



MODEL



TCAS simulation of a collision cascade for a **20 keV PKA** after recombination of close Frenkel pairs: Initial distribution of vacancies after Φ_{eq} = 10¹⁴ cm⁻²



[R. Radu et al., JAP 117, 164503 (2015)]

[M. Huhtinen, NIM A 491, (2002) 194]

→distribution of vacancies and interstitials approx. straight line







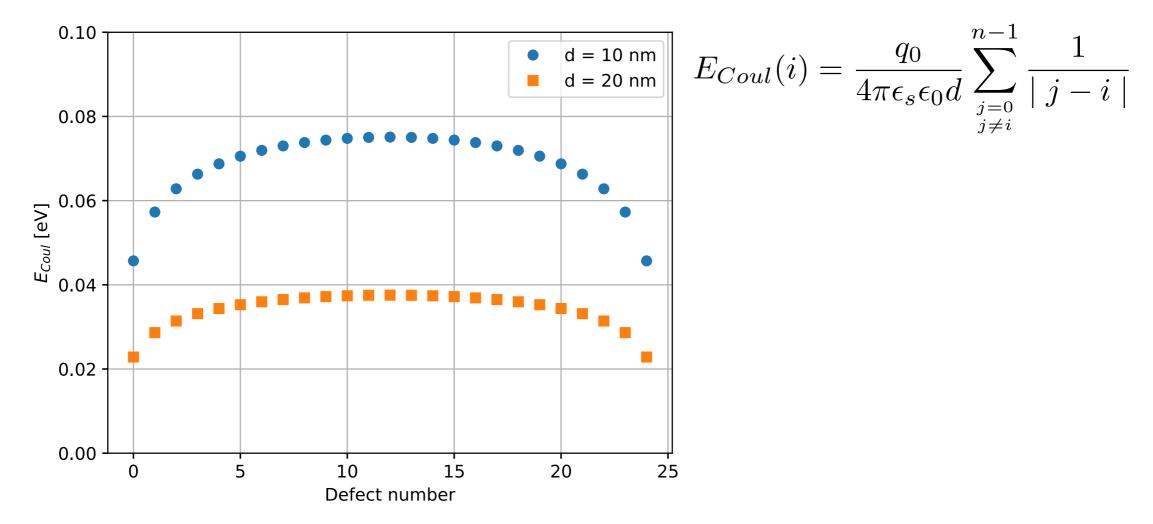
Assume:

n **uniformly spaced** point defects on a straight line, deep acceptor, negatively charged

ightarrow Coulomb repulsion

Energy scale: $E_{Coul} = \frac{q_0}{4\pi\epsilon_0\epsilon_{Si}d} = 0.121 \,\mathrm{eV/d[nm]}$

Example: n = 25 (arbitrary), distance between 2 charged defects d = 10/20 nm





MODEL



 $E_a(f_t) = E_0 - \Delta E_a \cdot f_t$

 $E_a(f_t)$

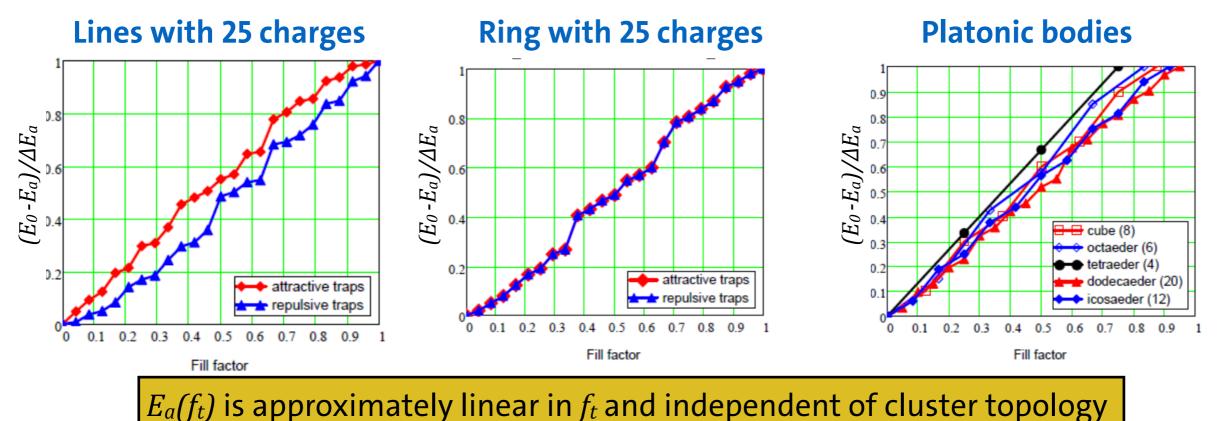
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Procedure:

- All n defect states **occupied** \rightarrow calculate Coulomb energy $E_{Coul}(n_t)$

 $\rightarrow E_a(n_t) = E_0 - E_{Coul}(n_t) = E_{min}$; fill factor $f_t = n_t/n = 1$

- Carrier with **highest** energy is **emitted** $E_a(n_t-1) = E_0 - E_{Coul}(n_t-1)$; $f_t = (n_t-1)/n$
- New E_{Coul} for every left carrier \rightarrow carrier with highest E_{Coul} emitted $\rightarrow E_a(n_t-2)$
- Successive calculation of $E_{Coul}(i)$ until last carrier emitted $\rightarrow E_{Coul}(1) = 0$
 - $\rightarrow E_a(\mathbf{0}) = E_0 = E_{max}; f_t = \mathbf{0}$





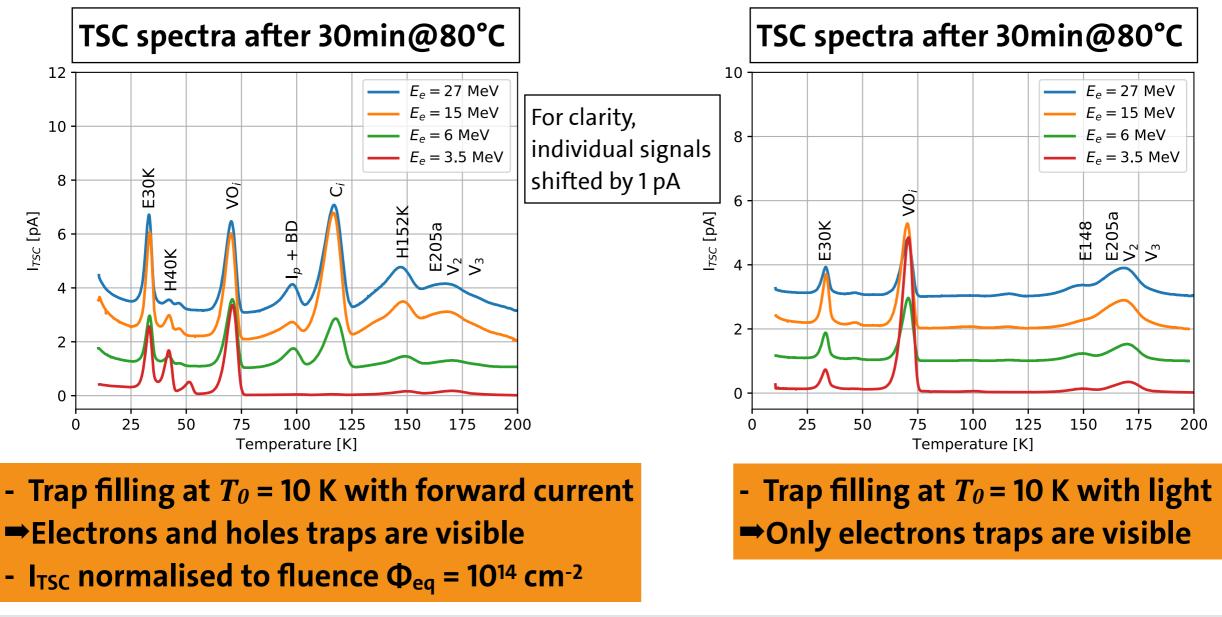


Implement $E_a(f_t)$ in TSC calculation, e.g. for acceptor traps (SRH-statistics): $I_{TSC}(T) = \frac{q_0 \cdot A \cdot d}{2} \cdot e(T) \cdot f_t(T) (N_t)$ **Density of defects TSCurrent:** in all clusters $e(T) = \sigma_n \cdot v_{th,n}(T) \cdot N_C(T) \cdot \exp\left(-\frac{E_a(f_t)}{k_P T}\right)$ **Emission rate:** Fraction of filled states: $f_t(T) = \exp\left(-\frac{1}{\beta}\int_{T_0}^T e(T') dT'\right)$ with β the heating rate **Effective energy:** $E_a(f_t) = E_0 - \Delta E_a \cdot f_t$ **Example:** 10 $\Delta E_a = 0 \text{ meV}$ The T-dependence of the effective $\Delta E_a = 5 \text{ meV}$ $\Delta E_a = 10 \text{ meV}$ $\Delta E_a = 20 \text{ meV}$ energy E_a via $f_t(T)$ leads to a shift and broadening of the TSC-peak 6 I_{TSC} [pA] 4 **Calculations for** $N_t = 5 \cdot 10^{11} \,\mathrm{cm}^{-3}$ 2 $\sigma_n = 5 \cdot 10^{-14} \text{ cm}^{-2}$ $E_0 = 0.175 \text{ eV}$ 55 60 65 70 75 80 50 $T_0 = 10 \text{ K}$ Temperature [K]





- Samples: FZ n-type pad diodes of 0.25 cm² area and 283 μ m thickness
- Irradiation: With electrons of 3.5, 6, 15 and 27 MeV kinetic energy
- TSC measurements (Phd thesis R. Radu + R. Radu et al., JAP 117, 164503 (2015)):
- For 15 MeV isochronal annealing for Δt =30 min at T_{ann} = 80 -280°C, in 20°C steps
- After annealing of 30 min at T_{ann} = 80°C for the other energies





VACANCY-OXYGEN DEFECT

from literature

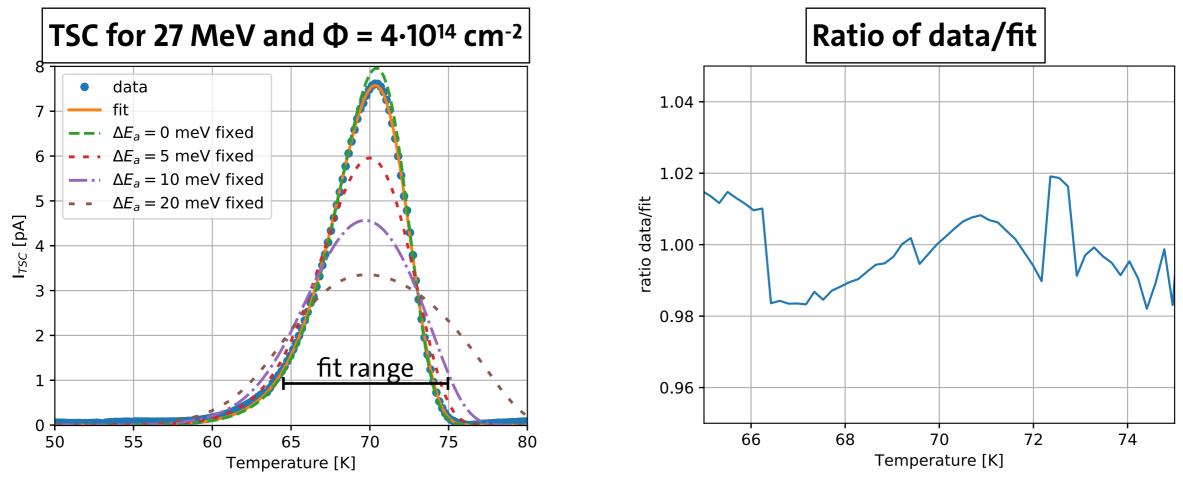


Vacancy-oxygen (VO_i) defect:

- Acceptor at approx. 70 K
- Known to be point-like defect
- Energy level at E_C 0.176 eV
- $\sigma_n \approx 7.9 \cdot 10^{-15} \text{ cm}^{-2}$

Ansatz:

- Fit cluster model
- Free parameters: N_{t} , σ_{n} , ΔE_{a}
- $\delta I/I = 1\%$ uncertainty



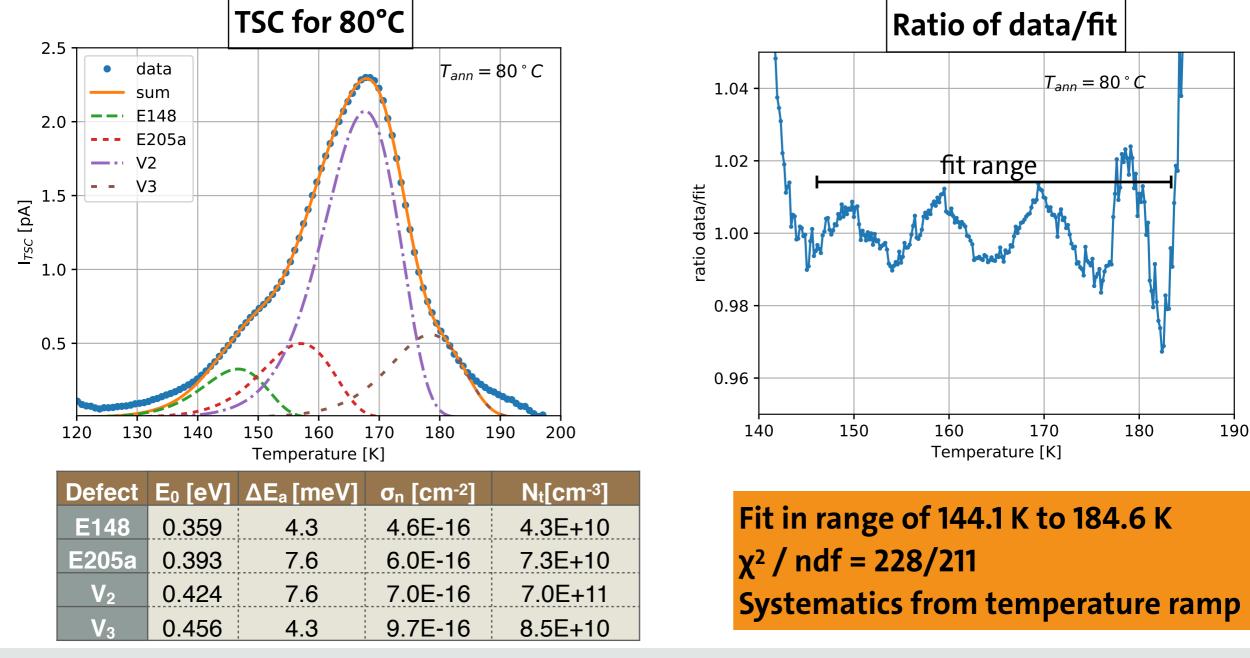
Fit in the range of 64.5 K to 75.0 K results in $\Delta E_a = 0.9$ meV and $\sigma_n = 7.99 \cdot 10^{-15}$ cm⁻² with χ^2 / ndf = 61.4/48. Fits with fixed ΔE_a values, which differ significantly from zero are excluded. \rightarrow SRH provides a good description of point defects





Isochronal annealing for 15 MeV and $\Phi = 2.6 \cdot 10^{14} \text{ cm}^{-2}$

- Fit cluster model for E148, E205a, V_2 , V_3 with energies E_0 from literature
- Free parameters are N_t , σ_n , ΔE_a
- Additional assumption: Same ΔE_a for E148 and V₃ and same ΔE_a for E205a and V₂

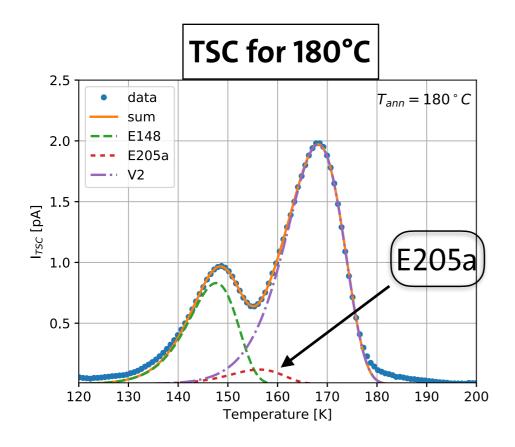


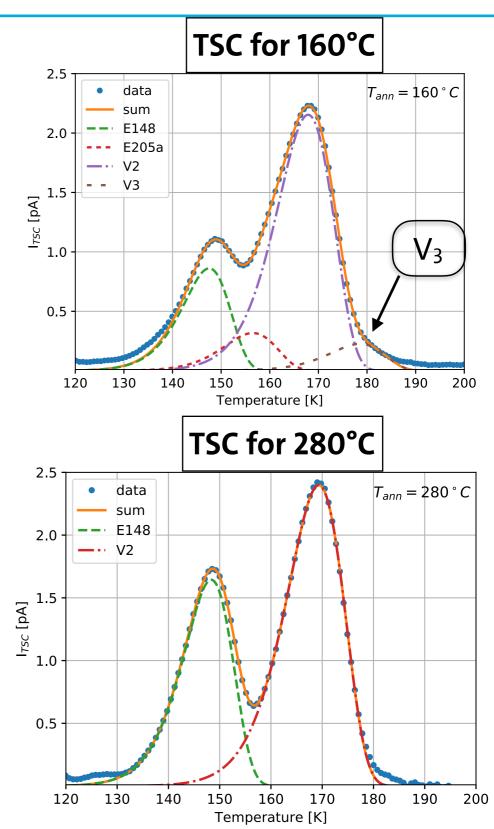




TSC for 15 MeV isochronal annealing

- Annealing out of V₃ at 180°C
- Annealing out of E205a at 200°C
- Fit ranges:
- 160 °C: 144 185 K
- 180 °C: 141 176 K
- 280 °C: 138 178 K

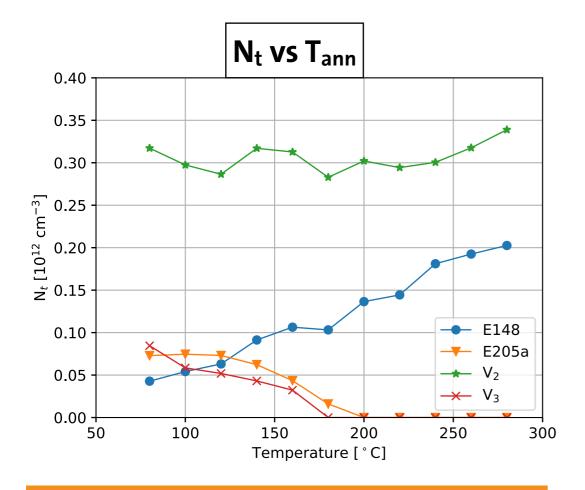






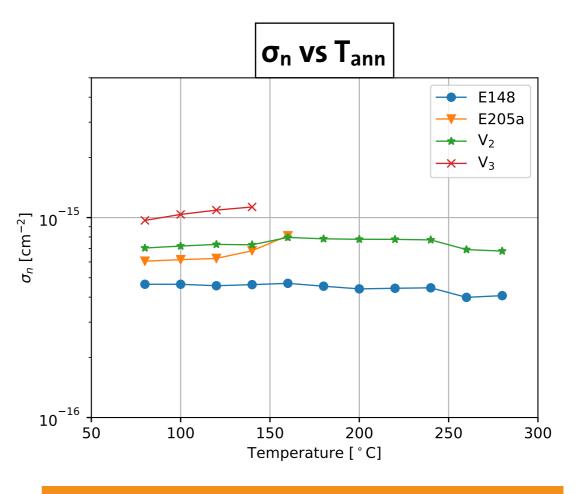


Fit results for trap concentrations and cross sections:



- Annealing out of E205a and V₃

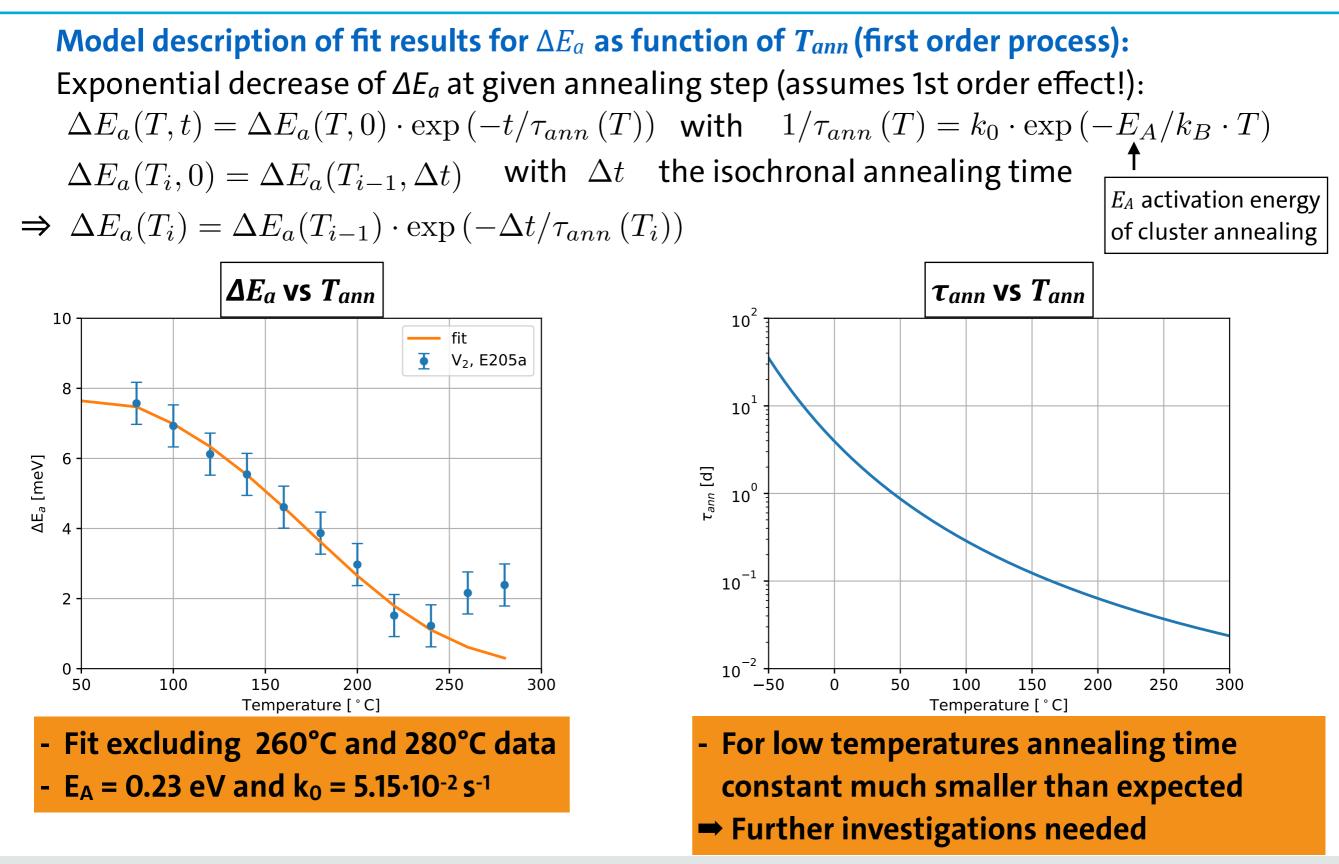
- V₂ concentration nearly constant
- E148 concentration increases



- Only small variation of the cross sections as function of *T*_{ann}







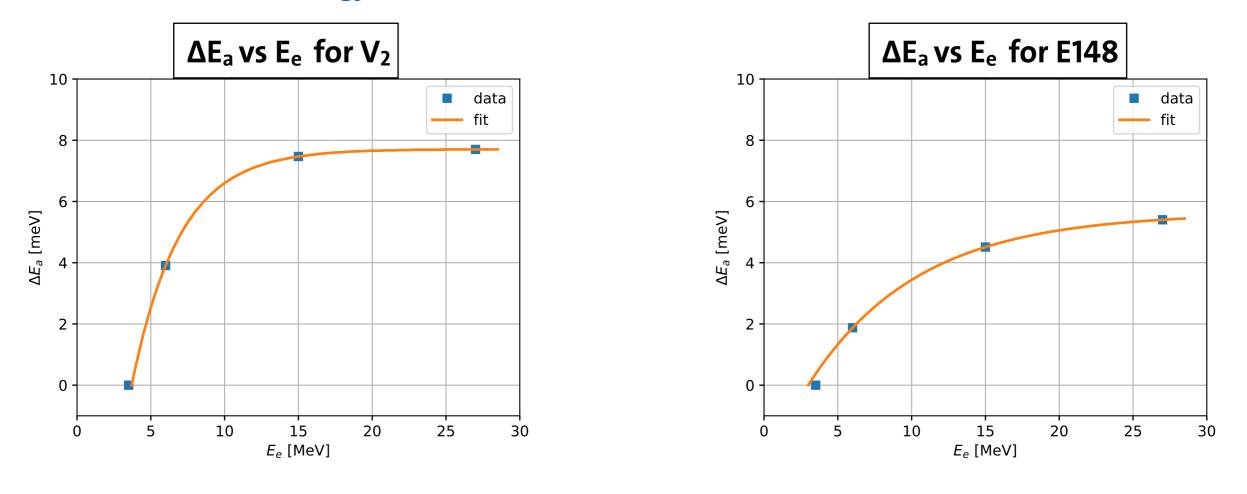




Electron-energy dependence of cluster formation :

Parametrisation for E_e > E_{th}:
$$\Delta E_a = A \cdot \left[1 - \exp\left(\frac{E_e - E_{th}}{\gamma_e}\right)\right]$$

with threshold energy E_{th}



Extracted threshold energies: - V_2 : E_{th} = 3.7 MeV (A = 7.7 meV, γ_e = 3.2 MeV) - E148 : E_{th} = 3.0 MeV (A = 5.6 meV, γ_e = 7.4 MeV)





- 1. Model within SRH statistics developed, which allows describing point + cluster defects
- 2. Model applied to TSC data with light injection for pad diodes irradiated by electrons with $E_e = 3.5 27$ MeV where cluster formation is expected for $E_e \ge 7$ MeV
- 3. Analysis VO_i: confirm point defects
- 4.Analysis region 0.35- 0.5 eV from the conduction band edge, where there are 4 overlapping states:
 - evidence for cluster defects
 - as function of annealing, change of concentration + dissociation of clusters
- 5. Assuming a first order effect for modelling the T-dependence of cluster dissociation indicates significant effects at room T and even at -30°C. However, more work needed.

Thank you for your attention!





Backup